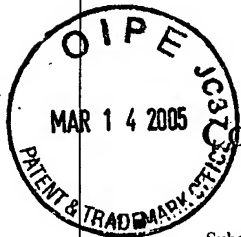


RCE
JAN



REQUEST
FOR
CONTINUED EXAMINATION (RCE)
TRANSMITTAL

Subsection (b) of 35 U.S.C. § 132, effective on May 29, 2000,
provides for continued examination of an utility or plant application
filed on or after June 8, 1995.
See The American Inventors Protection Act of 1999 (AIPA).

Application Number	10/602,315
Filing Date	June 24, 2003
First Named Inventor	Kie Y. Ahn
Group Art Unit	2829
Examiner Name	Asok K. Sarkar
Attorney Docket Number	1303.107US1
Customer No.	21186

This is a Request for Continued Examination (RCE) under 37 CFR § 1.114 of the above-identified application entitled LANTHANIDE OXIDE / HAFNIUM OXIDE DIELECTRICS.

Submission required under 37 C.F.R. § 1.114

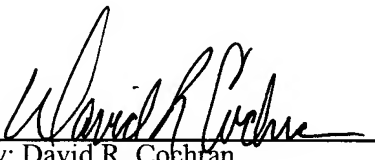
1. ☐ Consider the amendment(s)/reply under 37 C.F.R. § 1.116 previously filed on .
2. ☐ Consider the arguments in the Appeal Brief or Reply Brief previously filed on .
3. ☐ An Amendment Under 37 CFR § 1.116 (pages) is enclosed.
4. ☐ A new power of attorney (pages) is enclosed.
5. ☒ An Information Disclosure Statement is enclosed (2 pages).
 - a. 1 Form(s) 1449
 - b. 2 Copies of IDS Citations
6. ☒ A check in the amount of \$790.00 is attached to pay the RCE filing fee required under C.F.R. § 1.17(e).
7. ☒ **The Commissioner is hereby authorized to credit overpayments or charge any fees set forth in 37 CFR §§ 1.16 through 1.18 to Deposit Account No. 19-0743.**
8. ☐ A Petition for Extension of Time in the prior application (pages) is enclosed along with a check in the amount of to pay the extension fee.
9. ☒ Others: Communication Concerning Related Applications (2 pgs.).

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

03/15/2005 YPOLITE1 00000032 10602315

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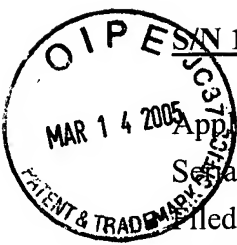
01 FC:1801

By: 
Atty: David R. Cochran
Reg. No. 46,632

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: Attn-Mail Stop RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 10 day of March, 2005.

KACIA LEE
Name

Kacia Lee
Signature



SN 10/602,315

PATENTIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kie Y. Ahn et.al.

Examiner: Asok K. Sarkar

Serial No.: 10/602,315

Group Art Unit: 2829

Filed: June 24, 2003

Docket: 1303.107US1

Title: LANTHANIDE OXIDE / HAFNIUM OXIDE DIELECTRICS

COMMUNICATION CONCERNING RELATED APPLICATION(S)

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Applicants would like to bring to the Examiner's attention the following related application(s) in the above-identified patent application:

<u>Serial/Patent No.</u>	<u>Filing Date</u>	<u>Attorney Docket</u>	<u>Title</u>
11/036296	January 14, 2005	1303.030US2	LOW-TEMPERATURE GROWN HIGH QUALITY ULTRA-THIN CoTiO ₃ GATE DIELECTRICS
10/909959	August 2, 2004	1303.114US1	ATOMIC LAYER DEPOSITION OF ZIRCONIUM-DOPED TANTALUM OXIDE FILMS
10/931533	August 31, 2004	1303.119US1	ATOMIC LAYER DEPOSITED TITANIUM ALUMINUM OXIDE FILMS
10/926812	August 26, 2004	1303.121US1	RUTHENIUM GATE FOR A LANTHANIDE OXIDE DIELECTRIC LAYER
10/930167	August 31, 2004	1303.122US1	ATOMIC LAYER DEPOSITED LANTHANUM ALUMINUM OXIDE DIELECTRIC LAYER
11/010529	December 13, 2004	1303.126US1	ATOMIC LAYER DEPOSITED LANTHANUM HAFNIUM OXIDE DIELECTRICS
11/029757	January 5, 2005	1303.127US1	ATOMIC LAYER DEPOSITED HAFNIUM TANTALUM OXIDE DIELECTRICS

11/010766	December 13, 2004	1303.129US1	HYBRID ALD-CVD OF PrXOY/ZrO2 FILMS AS GATE DIELECTRICS
11/053577	February 8, 2005	1303.131US1	ATOMIC LAYER DEPOSITION OF DY-DOPED HFO2 FILMS AS GATE DIELECTRICS
11/058563	February 15, 2005	1303.133US1	ATOMIC LAYER DEPOSITION OF Zr3N4/ZrO2 FILMS AS GATE DIELECTRICS
	February 23, 2005	1303.134US1	ATOMIC LAYER DEPOSITION OF Hf3N4/HfO2 FILMS AS GATE DIELECTRICS
11/031289	January 7, 2005	1303.069US3	LANTHANIDE DOPED TiOx DIELECTRIC FILMS BY PLASMA OXIDATION
11/059594	February 16, 2005	1303.046US2	EVAPORATED LaAlO3 FILMS FOR GATE DIELECTRICS

Respectfully submitted,


KIE Y. AHN ET AL.

By Applicants' Representatives,

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Minneapolis, MN 55402
(612) 371-2157

Date 9 MARCH 2005

By


David R. Cochran
Reg. No. 46,632

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Name

KACIA LEE

Signature

Kacia Lee